

**AMENDMENTS TO THE CLAIMS**

1. (withdrawn): A method for forming a light emitting diode comprising following steps:  
5 forming a first stack;  
forming a second reaction layer over said first stack;  
forming a second stack;  
forming a first reaction layer over said second stack;  
holding together said first reaction layer and said second reaction layer by means  
10 of a transparent adhesive layer.
2. (withdrawn): The method of claim 1 wherein the step of forming a first stack  
comprises following steps:  
providing a first substrate;  
15 forming a second contact layer on the first substrate;  
forming a second cladding layer on the second contact layer;  
forming an emitting layer on the second cladding layer;  
forming a first cladding layer on the emitting layer;  
forming a first contact layer on the first cladding layer; and  
20 forming a transparent conductive layer on the first contact layer.
3. (withdrawn): The method of claim 2 further comprising following steps:  
removing the first substrate;  
etching the second contact layer, the second cladding layer, the emitting layer,  
25 first cladding layer, and the first contact layer; and  
forming a first electrode on the second contact layer, and a second electrode on  
the transparent conductive layer.
4. (withdrawn): The method of claim 2 wherein the first substrate comprises at  
30 least one material selected from a group consisting of GaP, GaAs, and Ge.
5. (withdrawn): The method of claim 2 wherein the first contact layer and the

second contact layer each comprise at least one material selected from a group consisting of GaP, GaAs, GaAsP, InGaP, AlGaInP, and AlGaAs.

- 5 6. (withdrawn): The method of claim 2 wherein the first cladding layer, the emitting layer, and the second cladding layer each comprise AlGaInP.
- 10 7. (withdrawn): The method of claim 2 wherein the transparent conductive layer comprises at least one material selected from a group consisting of indium tin oxide, cadmium tin oxide, antimony tin oxide, zinc oxide, zinc tin oxide, BeAu, GeAu, and Ni/Au.
- 15 8. (withdrawn): The method of claim 1 wherein the first and second reaction layers each comprise at least one material selected from a group consisting of SiN<sub>x</sub>, Ti, and Cr.
9. (withdrawn): The method of claim 1 wherein the transparent adhesive layer comprises at least one material selected from a group consisting of PI, BCB, and PFCB.
- 20 10. (withdrawn): The method of claim 1 wherein forming a second stack comprises forming a second substrate.
- 25 11. (withdrawn): The method of claim 10 wherein the second substrate comprises at least one material selected from a group consisting of SiC, Al<sub>2</sub>O<sub>3</sub>, glass materials, quartz, GaP, GaAsP, and AlGaAs.
- 30 12. (withdrawn): The method of claim 1 wherein said first reaction layer and said second reaction layer are held together with the transparent adhesive layer by chemical bonds.
13. (withdrawn): The method of claim 12 wherein the chemical bonds are hydrogen bonds or ionic bonds.

14. (original): A light emitting diode comprising:  
a first stack;  
a second reaction layer formed on the first stack;  
5 a second stack;  
a first reaction layer formed on the second stack;  
a transparent adhesive layer formed between the first and second reaction layers;  
and  
a first electrode and a second electrode formed on the first stack.
- 10 15. (original): The light emitting diode of claim 14 wherein the first stack comprises:  
a transparent conductive layer formed on the second reaction layer, the  
transparent conductive layer having a first surface area and a second  
15 surface area;  
a first contact layer formed on the first surface area of the transparent conductive  
layer;  
a first cladding layer formed on the first contact layer;  
an emitting layer formed on the first cladding layer;  
20 a second cladding layer formed on the emitting layer; and  
a second contact layer formed on the second cladding layer;  
wherein the first electrode is formed on the second contact layer, and the second  
electrode is formed on the second surface area of the transparent  
conductive layer.
- 25 16. (original): The light emitting diode of claim 15 wherein the first contact layer  
and the second contact layer each comprise at least one material selected from a  
group consisting of GaP, GaAs, GaAsP, InGaP, AlGaInP, and AlGaAs.
- 30 17. (original): The light emitting diode of claim 15 wherein the first cladding layer,  
the emitting layer, and the second cladding layer each comprise AlGaInP.

18. (original): The light emitting diode of claim 15 wherein the transparent conductive layer comprises at least one material selected from a group consisting of indium tin oxide, cadmium tin oxide, antimony tin oxide, zinc oxide, zinc tin oxide, BeAu, GeAu, and Ni/Au.
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19. (original): The light emitting diode of claim 14 wherein the first and second reaction layers each comprise at least one material selected from a group consisting of SiNx, Ti, and Cr.
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20. (original): The light emitting diode of claim 14 wherein the transparent adhesive layer comprises at least one material selected from a group consisting of PI, BCB, and PFCB.
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21. (original): The light emitting diode of claim 14 wherein the second stack comprises a second substrate, the first reaction layer being formed on the second substrate.
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22. (original): The light emitting diode of claim 21 wherein the second substrate comprises at least one material selected from a group consisting of SiC, Al<sub>2</sub>O<sub>3</sub>, glass materials, quartz, GaP, GaAsP, and AlGaAs.